

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants : Gabriele Barlocchi et al.
Filed : September 18, 2003
For : METHOD FOR FORMING HORIZONTAL BURIED
CHANNELS OR CAVITIES IN WAFERS OF
MONOCRYSTALLINE SEMICONDUCTOR
MATERIAL

Docket No. : 854063.552D1
Date : September 18, 2003

Mail Stop Patent Application
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT


Commissioner for Patents:

In accordance with 37 C.F.R. §§ 1.56 and 1.97 through 1.98, applicants wish to make known to the Patent and Trademark Office the 13 references set forth on the attached Form PTO-1449. This application relies, under 35 U.S.C. § 120, on the earlier filing date of prior Application No. 09/545,260, filed April 7, 2000. The references listed on the attached Form PTO-1449 were submitted to and/or cited by the Patent and Trademark Office in this prior application and, therefore, are not required to be provided in this application. If the Examiner wishes, copies will be provided upon request. As to any reference supplied, applicants do not admit that it is "prior art" under 35 U.S.C. §§ 102 or 103, and specifically reserve the right to traverse or antedate any such reference, as by a showing under 37 C.F.R. § 1.131 or other method. Although the aforesaid references are made known to the Patent and Trademark Office in compliance with applicants' duty to disclose all information they are aware of which is believed relevant to the examination of the above-identified application, applicants believe that their invention is patentable.

Please acknowledge receipt of this Information Disclosure Statement and kindly make the cited references of record in the above-identified application.

Applicants believe this Information Disclosure Statement has been timely filed, however, the Commissioner is authorized to charge any fee due by way of this Information Disclosure Statement to our Deposit Account No. 19-1090.

Respectfully submitted,
Gabriele Barlocchi et al.
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FORM PTO-1449 (REV.7-80)	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DOCKET NO. 854063.552D1	APPLICATION NO.
INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)		APPLICANTS Gabriele Barlocchi et al.	
		FILING DATE September 18, 2003	GROUP ART UNIT

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	AA	4,579,621	04/01/86	Hine	156	612	
	AB	4,993,143	02/19/91	Sidner et al.	29	621.1	
	AC	5,659,138	08/19/97	Iwata et al.	73	514.33	
	AD	5,883,420	03/16/99	Mirza et al.	257	419	
	AE	5,926,721	07/20/99	Hong et al.	438	413	
	AF	5,889,872	03/30/99	Sooriakumar et al.	381	174	
	AG	6,093,330	07/25/00	Chong et al.	216	2	
	AH	6,180,480	01/30/01	Economikos et al.	438	386	
	AI	6,307,247	10/23/01	Davies	257	522	
	AJ						

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION	
					YES	NO
	AK	JP4114470	04/15/92	Japan (+abstract)		
	AL	JP9082983	03/28/97	Japan		
	AM					
	AN					
	AO					

OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)

	AP	Tabata, Osamu et al., "Anisotropic etching of silicon TMAH solutions", Sensors and Actuators, July 1992. Pages 51-57.
	AQ	Kovacs, Gregory T. A. et al., "Bulk Micromachining of Silicon", IEEE, August 1998. Vo. 86, No. 8, Pages 1536-1551.
	AR	

EXAMINER

DATE CONSIDERED

* EXAMINER: Initial if reference considered, whether or not criteria is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant(s).